SEP 06 2007 W

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:		
	Kei YOSHIKAWA et al.) Group Art Unit: 2624
Application No.: 09/662,219)) Examiner: Samir Anwar AHMED
Filed:	September 14, 2000) Confirmation No.: 9438
For:	PATTERN CORRECTING METHOD OF MASK FOR MANUFACTURING A SEMICONDUCTOR DEVICE AND RECORDING MEDIUM HAVING RECORDED ITS PATTERN CORRECTING METHOD)))))

Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

<u>AMENDMENT</u>

In reply to the Office Action mailed April 6, 2007, the period for response having been extended to September 6, 2007, by a request for extension of two months and fee payment filed concurrently herewith, please amend the above-identified application as follows:

Amendments to the Specification are included in this paper.

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks/Arguments follow the amendment sections of this paper.